



Software solutions
for optimizing micro
& nano fabrication



Australia BEAMeeting

BEAMeeting Melbourne 2025

Technical Workshop & Discussion



Time: Tuesday, February 18th, 2025 9:00 – 16:30 (AEST)
7:00 – 14:30 (CST/SST)

Location: RMIT City Campus, Kaleide Theatre
Online via TEAMS (access data will be sent after registration shortly before BEAMeeting)

Organizers: GenISys GmbH, RMIT University

BEAMeetings are a technical exchange platform for the direct write community focused on e-Beam and laser lithography, data-preparation, PEC, process correction, lithography simulation, and metrology. It is a platform for BEAMER users and those who are interested in GenISys software.

As in the past, it is a great opportunity to meet with the GenISys team, have face to face in-depth discussions, exchange ideas and position your needs and wishes. On top of standard BEAMER/TRACER/LAB, this year we would like to emphasize ProSEM, our full metrology solution for the microscopy team of nano fabrication center.

Please save the date in your calendar and register our BEAMeeting:

On-Site in Melbourne – [REGISTER here](#)

Online via TEAMS – [REGISTER here](#)

or visit our Homepage for the details: [BEAMeeting Melbourne 2025](#).

The BEAMeeting is free of charge. Please feel free to share this information with interested colleagues who may wish to join the BEAMeeting.

Please do not hesitate to contact us (marketing@genisys-gmbh.com) if you have any questions or any suggestions.

We are looking forward to presenting you with an interesting and valuable workshop!

Thank you,
The GenISys Team

Australia BEAMeeting Agenda 2025

Tuesday, February 18th		
Nit Taksatorn & Vijay Sivan GenISys & RMIT University	Opening	09:00
Sven Bauerdick GenISys	Advanced SEM Metrology: Tools & Applications	09:15
Elliot Cheng University of Queensland	Automating Large SEM Data Sets for Improved Photonics Fabrication	10:00
Morning Tea		10:30
Nezih Ünal GenISys	GenISys Corporate Update	11:00
Vijay Sivan RMIT University	Voyager BEAMER Data Preparation with FBMS Framing	11:30
Lunch		12:00
Nit Taksatorn GenISys	LAB E-Beam and Laser Simulation	13:30
Michael Stuibler MCN	Sequence Writing and JPG/BMP File Exposure	14:00
Satoshi Shimizu GenISys	BEAMER Strategies to Improve CD Linearity and Pattern Fidelity on MLA Exposure Tools	14:30
Afternoon Tea		15:00
Chun-Ching Chu University of Queensland	Applications of Electron Beam Lithography on Superconducting Devices	15:30
Thomas Michels GenISys	BEAMER & TRACER Update	16:00